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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Sherman
Appl. No. : 10/683,727
Filed : October 10, 2003
For : SEQUENTIAL CHEMICAL
VAPOR DEPOSITION
Examiner : Kelly M. Stouffer
Group Art Unit : 1762
Confirmation No. : 1627

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April 15, 2008

(Date)



Andrew N. Merickel, Reg. No. 53,317

AMENDMENT AND RESPONSE TO OFFICE ACTION

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The present paper is submitted in response to the final Office Action dated December 28, 2007 and is accompanied by a request for a one-month extension of time. Applicant appreciates the Examiner's willingness to consider the remarks herein in light of the interview conducted on February 23, 2008. The amendments simply cancel several claims and are believed to place the application in condition for allowance.

Amendments to the Claims begins on page 2 of this paper.

Summary of Interview begins on page 3 of this paper.

Remarks/Arguments begin on page 4 of this paper.